



ADMISSION TO DOCTORAL STUDIES

Session September 2026

Field of doctoral studies: **Materials engineering**

Doctoral supervisor: **Professor Daniel MUNTEANU**

TOPICS FOR THE ADMISSION TO DOCTORAL STUDIES

TOPIC 1: Correlations regarding the effects of plasma activation of metallic surfaces (substrate), their wetting capacity and the adhesion of deposited hard coatings.

Contents / Main aspects to be considered:

- Preparation of metallic substrates and their activation by plasma treatments, using different activation regimes.
- Determination of the wetting capacity of surfaces by evaluating the contact angle.
- Deposition of thin layers by the reactive sputtering process in magnetron regime.
- Determination of the adhesion of thin layers, by different specific methods.

Recommended bibliography:

1. Alexandru Danchiv, Hidraulică aplicată; elemente de hidraulică generală și subterană. Editura Universității din București – 2000.
2. Donald M. Mattox, **Handbook of Physical Vapor Deposition (PVD) processing**, Second Edition 2010.
3. I. Iliuc, **Tribologia straturilor subtiri**, Ed. Academiei Romane, 1974.
4. D.S. Rickerby, A. Matthews, **Advanced Surface coatings – a Handbook of Surface Engineering**, Springer Science + Business Media New York, 1991.

Prerequisites / Remarks: *to be adapted/ completed/ deleted*

Scientific Doctorate

Professional Doctorate

without tuition fee (state budget funded)

with tuition fee or with funding from other sources than the state budget

TOPIC 2: Specially designed architectures of thin films; application in chemical sensing.

Contents / Main aspects to be considered:

- Advanced materials for bio- and chemical sensing, based on nanostructured thin films.
- The Physical Vapour Deposition (PVD) method; fundamentals. The Magnetron – sputtering deposition process.
- Design, development, fabrication, and evaluation of different types of innovative sensors based on bi/tri-layered nanostructured thin films, produced by reactive magnetron sputtering.

Recommended bibliography:

1. Donald M. Mattox, **Handbook of Physical Vapor Deposition (PVD) processing**, Second Edition 2010.

2. D.S. Rickerby, A. Matthews, **Advanced Surface coatings – a Handbook of Surface Engineering**, Springer Science + Business Media New York, 1991.
3. "Chemical Sensors: A Global Market Report" by Global Industry Analysts, Inc, 2010.
4. G. Eranna, B.C. Joshi, D.P. Runthala and R.P. Gupta, "Oxide Materials for Development of Integrated Gas Sensors - A Comprehensive Review", *Critical Reviews in Solid State and Materials Sciences*, 29 (2004) 111.
5. A. Berna, "Metal Oxide Sensors for Electronic Noses and Their Application to Food Analysis", *Sensors* 10 (2010) 3882.
6. J. Homola, S.S. Yee and G. Gauglitz, "Surface plasmon resonance sensors: review", *Sensors and Actuators B* 54 (1999) 3.
7. C. Nylander, B. Liedberg and T Lind, "Gas detection by means of surface plasmon resonance", *Sensors and Actuators* 3 (1982) 79.
8. S.A. Maier, "Plasmonics: Fundamentals and Applications", Springer, New York, 2007.

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Doctoral supervisor,

Prof. dr. eng. Daniel MUNTEANU

Signature

Coordinator of the field of doctoral studies,

Prof. dr. eng. Mircea Horia ȚIEREAN

Signature